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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): MASUDA, et al
Serial No.: (not yet assigned)
Filed: August 26, 2003
For: PLASMA ETCHING APPARATUS AND PLASMA ETCHING
METHOD

REAFFIRMATION OF CLAIM FOR PRIORITY

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

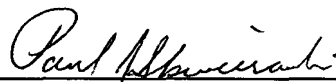
August 26, 2003

Sir:

Under the provisions of 35 USC §119 and 37 CFR §1.55, Applicants hereby claim the right of priority based on Japanese Patent Application No. 7-057472, filed in Japan on March 15, 1995.

The certified copy of the above-referred to Japanese Patent Application was filed on May 28, 1996 in prior application 08/611,758, filed March 8, 1996.

Respectfully submitted,



Paul J. Skwierawski
Registration No. 32,173
ANTONELLI, TERRY, STOUT & KRAUS, LLP

PJS/MK/cee
(703) 312-6600